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THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: KATSUMATA et al.

Atty. Dkt.: 01-570

Serial No.: 10/791,762

Art Unit: 2812

Filed: 3/4/2004

Examiner: TSAI

Title: METHOD OF MANUFACTURING  
SEMICONDUCTOR PRESSURE SENSOR

Commissioner for Patents  
U.S. Patent and Trademark Office  
220 20<sup>th</sup> Street S.  
Customer Window, Mail Stop Amendment  
Crystal Plaza Two, Lobby, Room 1B03  
Arlington, VA 22202

Date: 28 October 2004

**AMENDMENT UNDER 37 CFR 1.111**

Sir:

In response to the office action mailed 28 October 2004, please consider as follows:

**Amendments to the Claims** are reflected in the listing of claims that begins on page 2 of this paper.

**Remarks** begin on page 5 of this paper.